

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Basceri et al.
App. No.	:	Unknown
Filed	:	Herewith
For	:	HAZE-FREE HIGH BST FILMS
Examiner	:	Unknown
Group Art Unit	:	Unknown

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing 15 references that are also enclosed. This Information Disclosure Statement is being submitted at the time of filing of this application, and no fee is required in accordance with 37 C.F.R. § 1.97(b)(1), (b)(2), or (b)(4).

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 6/27/03

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FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MICRON.098CDV1	APPLICATION NO. Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)		APPLICANT Basceri et al.	
		FILING DATE Herewith	GROUP Unknown

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	1	5,335,138	08/02/94	Sandhu et al.			
	2	5,406,445	04/11/95	Fujii et al.			
	3	5,506,166	04/09/96	Sandhu et al.			
	4	5,717,234	02/10/98	Si et al.			
	5	5,781,404	07/14/98	Summerfelt et al.			
	6	5,783,253	07/21/98	Roh			
	7	5,889,299	03/30/99	Abe et al.			
	8	5,973,911	10/26/99	Nishioka			
	9	6,010,931	01/04/00	Sun et al.			
	10	6,117,482	09/12/00	Kawahara et al.			
	11	6,136,639	10/24/00	Seon			
	12	6,319,764 B1	11/20/01	Basceri et al.			

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	13	Hiromi Itoh et al., "Integration of BST Thin Film for Dram Fabrication", Integrated Ferroelectrics, 1995 Vol. 11, pp 101-109
	14	C. Basceri, "An Important Failure Mechanism in MOCVD (Ba,Sr)TiO ₃ Thin Films: Resistance Degradation", Ferroelectric Thin Films IV, Materials Research Society, Symposium Proceedings Volume 493, 1998, pp. 9-14
	15	Chung Ming Chu and Pang Lin, "Electric Properties and Crystal Structure of a (Ba,Sr)TiO ₃ Films Prepared at Low Temperatures on a LaNiO ₃ Electrode by Radio-Frequency Magnetron Sputtering", Appl. Phys. Lett., Vol. 70 (2), 13 January 1997, pp.249-51.

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EXAMINER	DATE CONSIDERED
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	